

Docket Number: 081468-0306524
Client Reference: P-0381.020-US

PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In Re the Application of

LOF et al.

Group Art Unit:

Application No.: TO BE ASSIGNED

Examiner:

Filed: November 12, 2003

Confirmation No.:

For: LITHOGRAPHIC APPARATUS AND DEVICE MANUFACTURING METHOD

INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents
P. O. Box 1450
Alexandria, VA 22313-1450

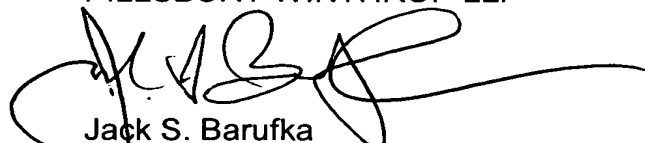
Sir:

Pursuant to 37 CFR 1.56, the attention of the Patent and Trademark Office is hereby directed to the references listed on the attached PTO-1449. It is respectfully requested that the information be expressly considered during the prosecution of this application, and that the references be made of record therein and appear among the "References Cited" on any patent to issue therefrom.

This Information Disclosure Statement is being filed (a) within three months of the U.S. filing date of this non-CPA application, OR (b) before the mailing date of the first Office Action on the merits in the present application. No certification or fee is required.

Respectfully Submitted,

PILLSBURY WINTHROP LLP



Jack S. Barufka
Registration Number 37087

Date: November 12, 2003

P.O. Box 10500
McLean, VA 22102
Telephone: (703) 905-2000
Facsimile: (703) 905-2500

Atty. Dkt. No.	M#	Client Ref.
	306524	P-0381.020-US

INFORMATION DISCLOSURE STATEMENT BY APPLICANT

Applicant: Joeri LOF *et al.*

Appln. No.: TO BE ASSIGNED

Filing Date: November 12, 2003

Date: November 12, 2003 Page 1 of 3

Examiner: Unknown Group Art Unit: Unknown

U.S. PATENT DOCUMENTS

Examiner's Initials*		Document Number	Date MM/YYYY	Name (Family Name of First Inventor)	Class	Sub Class	Filing Date (if appropriate)
	AR	3,573,975	04/1971	Dhaka <i>et al.</i>	117	212	
	BR	3,648,587	03/1972	Stevens	95	44	
	CR	4,346,164	08/1982	Tabarelli <i>et al.</i>	430	311	
	DR	4,396,705	08/1983	Akeyama <i>et al.</i>	430	326	
	ER	4,480,910	11/1984	Takanashi <i>et al.</i>	355	30	
	FR	4,509,852	04/1985	Tabarelli <i>et al.</i>	355	30	
	GR	5,040,020	08/1991	Rauschenbach <i>et al.</i>	355	53	
	HR	5,121,256	06/1992	Corle <i>et al.</i>	359	664	
	IR	5,610,683	03/1997	Takahashi	355	53	
	JR	5,715,039	02/1998	Fukuda <i>et al.</i>	355	53	
	KR	5,825,043	10/1998	Suwa	250	548	
	LR	5,900,354	05/1999	Batchelder	430	395	
	MR	6,191,429	02/2001	Suwa	250	548	
	NR	6,560,032	05/2003	Hatano	359	656	

FOREIGN PATENT DOCUMENTS

		Document Number	Date MM/YYYY	Country	Inventor Name		English Abstract		Translation Readily Available	
							Enclosed	No	Enclose	No
	OR	WO 99/49504	09/1999	PCT	Fukami <i>et al.</i>		X		X	
	PR	EP 0023231	02/1981	Europe	Tabarelli <i>et al.</i>		X			
	QR	EP 0418427	03/1991	Europe	Miyake		X		X	
	RR	EP 1039511	09/2000	Europe	Murakimi <i>et al.</i>		X		X	
	SR	DD 224448	07/1985	German	Hesse <i>et al.</i>			X		
	TR	DD 242880	02/1987	German	Kuch			X		
	UR	FR 2474708	07/1981	France	Letellier			X		
	VR	JP 62-065326	03/1987	Japan	Moriuchi		X			
	WR	JP 62-121417	06/1987	Japan	Nakazawa		X			
	XR	JP 63-157419	06/1988	Japan	Nakasuji		X			

OTHER (Including in this order Author, Title, Periodical Name, Date, Pertinent Pages, etc.)

	YR	EP Search Report for EP 02257938 dated September 25, 2003								
	ZR	M. Switkes <i>et al.</i> , "Immersion Lithography at 157 nm", MIT Lincoln Lab, Orlando 2001-1, December 17, 2001								
	AAR	M. Switkes <i>et al.</i> , "Immersion Lithography at 157 nm", J. Vac. Sci. Technol. B., Vol. 19, No. 6, November/December 2001, pp. 2353-2356								
	BBR	M. Switkes <i>et al.</i> , "Immersion Lithography: Optics for the 50 nm Node", 157 Anvers-1, September 4, 2002								

Examiner

Date Considered:

*EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP § 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to Applicant.

FORM PTO-1449 (modified)
 To: U.S. Department of Commerce
 (PW FORM PAT-1449)
 Patent and Trademark Office

Atty. •
 Dkt. No.

M#

Client Ref.

306781

P-0381.010-US

INFORMATION DISCLOSURE STATEMENT BY APPLICANT

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of

3

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U.S. PATENT DOCUMENTS

Examiner's Initials*		Document Number	Date MM/YYYY	Name (Family Name of First Inventor)	Class	Sub Class	Filing Date (if appropriate)
	CCR	6,603,130	08/2003	Bisschops <i>et al.</i>	250	492.1	
	DDR	6,633,365	10/2003	Suenaga	355	53	
	EER	2002/0163629	11/2002	Switkes <i>et al.</i>	355	53	
	FFR	2003/0123040	07/2003	Almog	355	69	
	GGR	2003/0174408	09/2003	Rostalski <i>et al.</i>	359	642	
	HHR						
	IIR						
	JJR						
	KKR						
	LLR						
	MMR						
	NNR						
	OOR						
	PPR						

FOREIGN PATENT DOCUMENTS

		Document Number	Date MM/YYYY	Country	Inventor Name		English Abstract		Translation Readily Available	
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	QQR	JP 04-305915	10/1992	Japan	Ozeki <i>et al.</i>		X			
	RRR	JP 04-305917	10/1992	Japan	Ozeki <i>et al.</i>		X			
	SSR	JP 06-124873	05/1994	Japan	Takahashi		X		X	
	TTR	JP 07-220990	08/1995	Japan	Fukuda <i>et al.</i>		X			
	UUR	JP 10-228661	08/1998	Japan	Kurokawa		X			
	VVR	JP 10-255319	09/1998	Japan	Suenaga <i>et al.</i>		X			
	WWR	JP 10-303114	11/1998	Japan	Suwa		X		X	
	XXR	JP 10-340846	12/1998	Japan	Kudo		X		X	
	YYR	JP 2001-091849	04/2001	Japan	Aizaki <i>et al.</i>		X			
	ZZR									

OTHER (Including in this order Author, Title, Periodical Name, Date, Pertinent Pages, etc.)

	AAAR	B.J. Lin, "Drivers, Prospects and Challenges for Immersion Lithography", TSMC, Inc., September 2002				
	BBBR	B.J. Lin, "Proximity Printing Through Liquid", IBM Technical Disclosure Bulletin, Vol.20, No. 11B, April 1978, p. 4997				

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	CCC					
	DDD					
	EEE					

FOREIGN PATENT DOCUMENTS

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							Enclosed	No	Enclose	No
	FFFF									
	GGG									

OTHER (Including in this order Author, Title, Periodical Name, Date, Pertinent Pages, etc.)

HHH	B.J. Lin, "The Paths To Subhalf-Micrometer Optical Lithography", SPIE Vol. 922, Optical/Laser Microlithography (1988), pp. 256-269				
IIIR	G.W.W. Stevens, "Reduction of Waste Resulting from Mask Defects", Solid State Technology, August 1978, Vol.21 008, pp. 68-72				
JJJR	S. Owa et al., "Immersion Lithography; its potential performance and issues", SPIE Microlithography 2003, 5040-186, February 27, 2003				
KKK	S. Owa et al., "Advantage and Feasibility of Immersion Lithography", Proc. SPIE 5040 (2003)				
LLL	Nikon Precision Europe GmbH, "Investor Relations - Nikon's Real Solutions", May 15, 2003				
MMM	H. Kawata et al., "Optical Projection Lithography using Lenses with Numerical Apertures Greater than Unity", Microelectronic Engineering 9 (1989), pp. 31-36				
NNN	J.A. Hoffnagle et al., "Liquid Immersion Deep-Ultraviolet Interferometric Lithography", J. Vac. Sci. Technol. B., Vol. 17, No. 6, November/December 1999, pp. 3306-3309				
OOO	B.W. Smith et al., "Immersion Optical Lithography at 193nm", FUTURE FAB International, Vol. 15, July 11, 2003				
PPP	H. Kawata et al., "Fabrication of 0.2µm Fine Patterns Using Optical Projection Lithography with an Oil Immersion Lens", Jpn. J. Appl. Phys. Vol. 31 (1992), pp. 4174-4177				
QQQ	G. Owen et al., "1/8µm Optical Lithography", J. Vac. Sci. Technol. B., Vol. 10, No. 6, November/December 1992, pp. 3032-3036				
RRR					
SSS					
TTT					
UUU					
VVV					
WWW					
XXX					
YYY					

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